

Form PTO 1449 U.S. Department of Commerce Patent and Trademark Office Information Disclosure Statement by Applicant	ATTY. DOCKET NUMBER NITT.0188	SERIAL NUMBER To be Assigned
	APPLICANT TAI et al.	
	FILING DATE Concurrently Herewith	GROUP

U.S. Patent Documents

Examiner Initial		DOCUMENT NUMBER	DATE	NAME	CLA SS	SUBC LASS	FILING DATE

Foreign Patent Documents

Examiner Initial		DOCUMENT NUMBER	FILING DATE	COUNTRY	CLASS	SUB- CLASS	TRANSLATION	
							YES	NO

Other Documents (Including Author, Title, Date Pertinent Pages, Etc.)

P.U.		James B. Boyce et al., "Laser Crystallization for Polycrystalline Silicon Device Applications", Technology and Applications of Amorphous Silicon, R.A. Street ed. (2000), pp. 95-146
P.U.		Akito Hara et al., "High Performance Poly-Si-TFTs on a Glass by a Stable Scanning CW Laser Lateral Crystallization", International Electron Devices Meeting (2001), pp. 747-750
P.U.		Mutsuko Hatano et al., "12.4L: Late News Paper: Selectively Enlarging Laser Crystallization Technology for High and Uniform Performance Poly-Si TFTs", SID 02 DIGEST (2002) pp. 158-161

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EXAMINER: Initial if citation is considered, whether or not citation is in conformance with MPEP 609; draw a line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant